

Fabrication of Microfluidic System by Hot Embossing and Selective Plasma
Surface Modification Method

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Abstract

The plasma surface modification to microfluid system gains many interests in recent years and many of these systems can be used for medical devices, food sensing and medicine development due to high accuracy and time consuming[1]. In this study, we fabricate the microfluidic system on PTFE materials by hot embossing method and modify the surfaces by selecting plasma parameters.

Keyword : Plasma. ePTFE